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**TRANSMITTAL
FORM**

(to be used for all correspondence after initial filing)

Application Number 10/655,997

Filing Date September 5, 2003

First Named Inventor Jon P. Daley

Art Unit 2812

Examiner Name Unknown

Total Number of Pages in This Submission

Attorney Docket Number MI22-2380

ENCLOSURES (Check all that apply)

- | | | |
|-----------------------------------------------------------------------------------|---------------------------------------------------------------------------|-----------------------------------------------------------------------------------------|
| <input type="checkbox"/> Fee Transmittal Form | <input type="checkbox"/> Drawing(s) | <input type="checkbox"/> After Allowance communication to Technology Center (TC) |
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| <input type="checkbox"/> Amendment/Reply | <input type="checkbox"/> Petition | <input type="checkbox"/> Appeal Communication to TC (Appeal Notice, Brief, Reply Brief) |
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| <input type="checkbox"/> Certified Copy of Priority Document(s) | <input type="checkbox"/> CD, Number of CD(s) _____ | |
| <input type="checkbox"/> Response to Missing Parts/Incomplete Application | Remarks | |
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NO FEE IS REQUIRED WITH THIS FILING.
However should a fee be determined as owing, please charge such fee to Deposit Account No. 23-0925.**SIGNATURE OF APPLICANT, ATTORNEY, OR AGENT**Firm or Individual name Mark S. Matkin; Reg. No. 32,268
Wells St. John P.S.

Signature

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CERTIFICATE OF TRANSMISSION/MAILING

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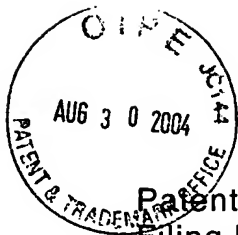
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This collection of information is required by 37 CFR 1.5. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to 2 hours to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

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EV372461141



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Patent Application Serial No. 10/655,997
Filing Date September 5, 2003
Inventor Jon P. Daley
Assignee Micron Technology, Inc.
Group Art Unit 2812
Examiner Unknown
Attorney Docket No. MI22-2380
Customer No. 021567
Title: Methods of Forming Patterned Photoresist Layers over Semiconductor
Substrates

INFORMATION DISCLOSURE STATEMENT

References -- See Attached Form PTO-1449

The attached form PTO-1449 is submitted in compliance with 37 CFR §1.56. Pursuant to 1276 OG 55, August 5, 2003, no copies of cited U.S. patents or U.S. patent application publications are included, as the date of filing of this patent application occurs after June 30, 2003. Copies of all other references are attached. No admission is made regarding whether all the listed references are prior art.

Citation of the referenced art is respectfully requested.

This Supplemental Information Disclosure Statement is being filed before the mailing date of a first Office Action. There, no fee is believed to be required.

However, in the event that a fee is required for filing this Information Disclosure Statement, please charge the fee specified under 37 C.F.R. § 1.17(p) to Deposit Account No. 23-0925.

Respectfully submitted,

Dated: 8-30-04

By: 

Mark S. Matkin
Reg. No. 32,268

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2380	SERIAL NO. 10/655,997
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT: Jon P. Daley	
				FILING DATE September 5, 2003	GROUP 2812

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AUG 30 2004
PATENT & TRADEMARK OFFICE

U.S. PATENT DOCUMENTS							
*Examiner's Initials	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
AA	4,086,074	04/78	Minot et al.				
AB	4,622,735	11/86	Shibata				
AC	4,683,645	08/87	Naguib et al.				
AD	4,693,910	09/87	Nakajima et al.				
AE	4,766,090	08/88	Coquin et al.				
AF	5,099,304	03/92	Takemura et al.				
AG	5,236,865	08/93	Sandhu et al.				
AH	5,444,024	08/95	Anjum et al.				
AI	5,470,784	11/95	Anjum et al.				

FOREIGN PATENT DOCUMENTS							
Document Number	Date	Country	Class	Subclass	Translation		
					Yes	No	
AJ							
AK							
AL							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)		
AM		ABSTRACT: Basceri et al., Atomic Layer Deposition for Nanoscale CU Metalization, 10 pages (pre-April 2004).
AN		En et al., Plasma immersion ion implantation reactor design considerations for oxide charging, 85 SURFACE AND COATINGS TECHNOLOGY 64-69 (1966).
AO		Ku et al., The Application of Ion Beam Mixing, Doped Silicide, and Rapid Thermal Processing of Self-Aligned Silicide Technology, 137 J. Electrochem. Soc. No. 2, pp. 728-740 (February 1990).
EXAMINER		DATE CONSIDERED

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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U.S. PATENT DOCUMENTS							
*Examiner's Initials	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
	AA	5,670,298	Hur				
	AB	6,037,239	Jennings				
	AC	6,096,621	Jennings				
	AD	6,130,140	Gonzalez				
	AE	6,133,105	Chen et al.				
	AF	6,133,116	Kim et al.				
	AG	6,177,235 B1	Francou et al.				
	AH	6,277,709 B1	Wang et al.				
	AI	6,277,728 B1	Ahn et al.				

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	Document Number	Date	Country	Class	Subclass	Translation	
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	AK						
	AL						

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)			
	AM		ABSTRACT: How to Eliminate Voiding in Porous-Low-k Dielectrics and The Mechanism of Void Formation; Lin et al.; 4 pages
	AN		COB Stack DRAM Cell Technology beyond 100 nm Technology Node; Yongjik Park & Kinam Kim; pp. 349.1 - 349.3;
	AO		Rubin et al., Shallow-Junction Diode Formation by implantation of Arsenic and Boron Through Titanium-Silicide Films and ..., 17 IEEE Transactions on Electron Devices, No. 1, pp. 183-190 (January 1990).
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*Examiner's Initials		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	6,440,793 B1	08/02	Divakaruni et al.			
	AB	6,465,325 B2	10/02	Ridley et al.			
	AC	6,720,638 B2	04/04	Tran			
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	AE						
	AF						
	AG						
	AH						
	AI						

FOREIGN PATENT DOCUMENTS								
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	AA	2001/0006759 A1	07/01	Shipley, Jr. et al.			
	AB	2002/0076879 A1	06/02	Lee et al.			
	AC	2002/0196651 A1	12/02	Weis			
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	AE						
	AF						
	AG						
	AH						
	AI						

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AA	10/689,958		Basceri			10/03	
AB	10/690,029		Derderian et al.			10/03	
AC	10/882,118		Sandhu et al.			04/04	
AD	10/879,367		Blalock et al.			06/04	
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AG							
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AI							

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